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PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 2828**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Daniel KOPF et al.

Group Art Unit: 2828

Application No.: 10/006,396

Examiner: D. NGUYEN

Filed: December 10, 2001

Docket No.: 111399

For: HIGH POWER AND HIGH GAIN SATURATION DIODE PUMPED LASER MEANS
AND DIODE ARRAY PUMPING DEVICE

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the August 25, 2005 final Office Action and in view of the November 22,
2005 personal interview, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.